

Exploring Cesium and H⁻ beam properties internal to the LANSCE H⁻ Ion Source using Resonant Absorption Spectroscopy and Cavity Ring Down Spectroscopy

David Kleinjan

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Co-authors: Gary Rouleau, Levi Neukirch (LANL)

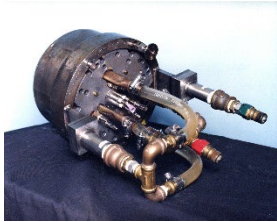
LANL LA-UR-22-30048

Outline

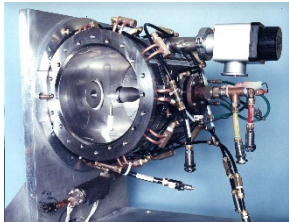
- 1.) LANSCE H- Ion Source review
- 2.) Motivation
- 3.) The LANSCE H- Ion Source Laser Diagnostic Stand
- 4.) Cs measurements using resonant absorption spectroscopy
 - *i.e.* Tunable Diode Laser Absorption Spectroscopy (TDLAS)
- 5.) Status of H- Beam density using Cavity Ring Down Spectroscopy (CRDS)



The Los Alamos Neutron Science Center (LANSCE)

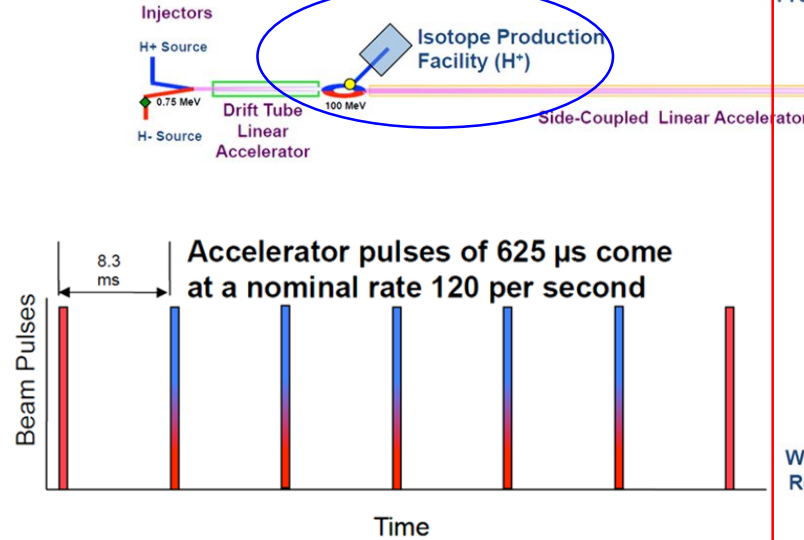


H+ Ion Source

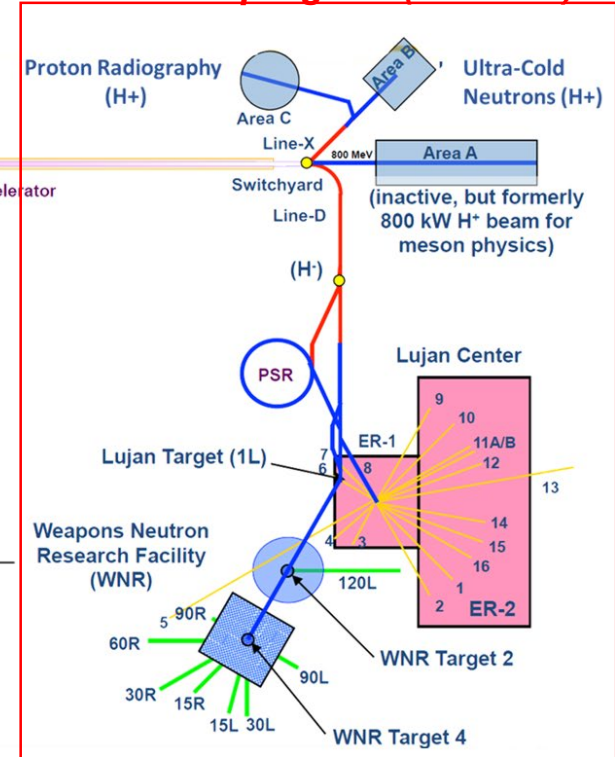


H- ion source

H+ beam program (~100 MeV)



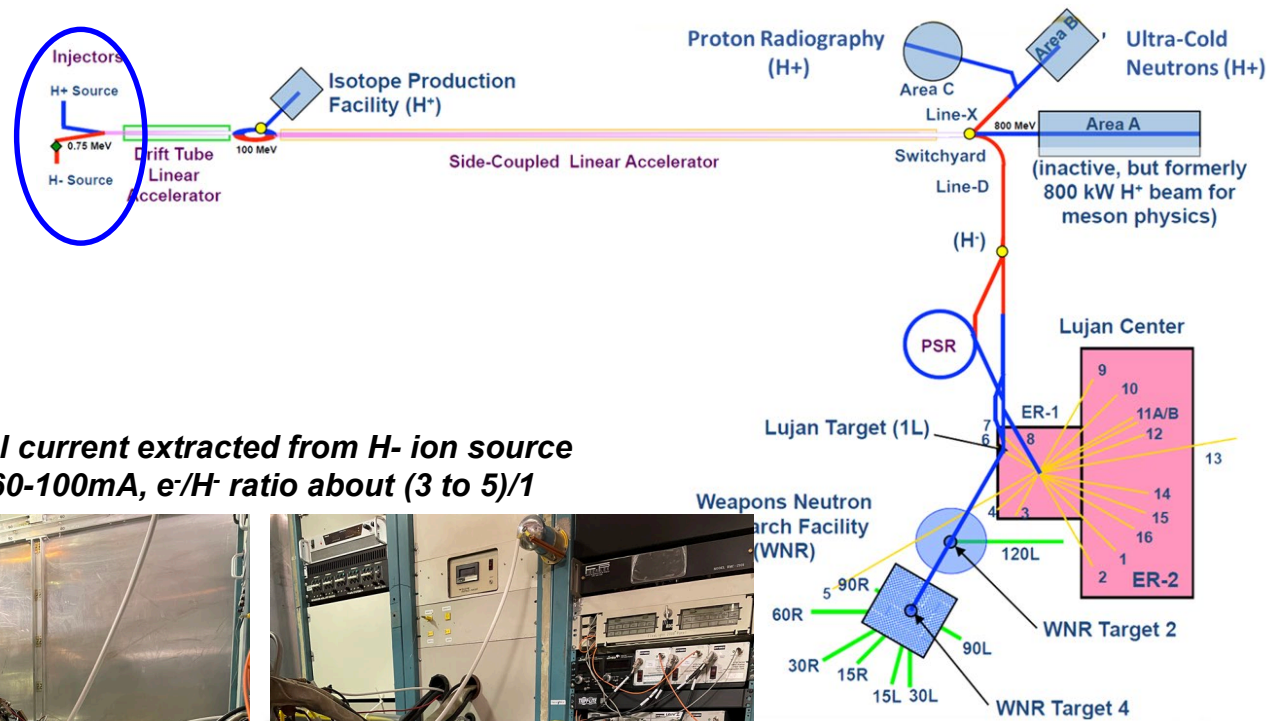
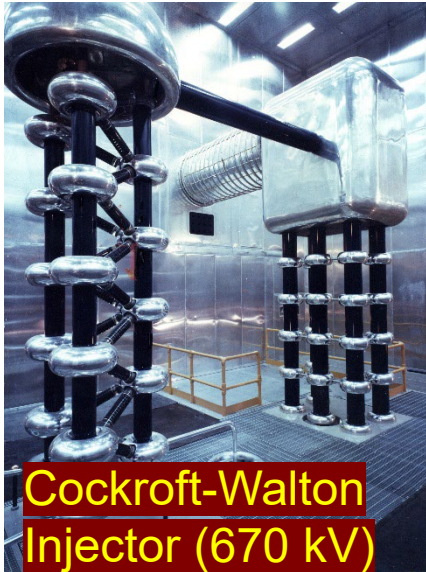
H- beam program (800 MeV)



- LANSCE Dual H⁺ and H⁻ beam programs
 - H⁺ beam one program
 - Isotope Production Facility
 - H⁻ beam multiple programs
 - (Proton Radiography, Lujan Center, WNR, Ultra-Cold Neutrons)
- The LANSCE H⁻ Ion Source
 - H⁻ ion source parameters
 - 120 Hz, 10% D.F. (833μs pulse)
 - 14-16 mA of H⁻ current
 - Ion Source recycle every 4-5 weeks



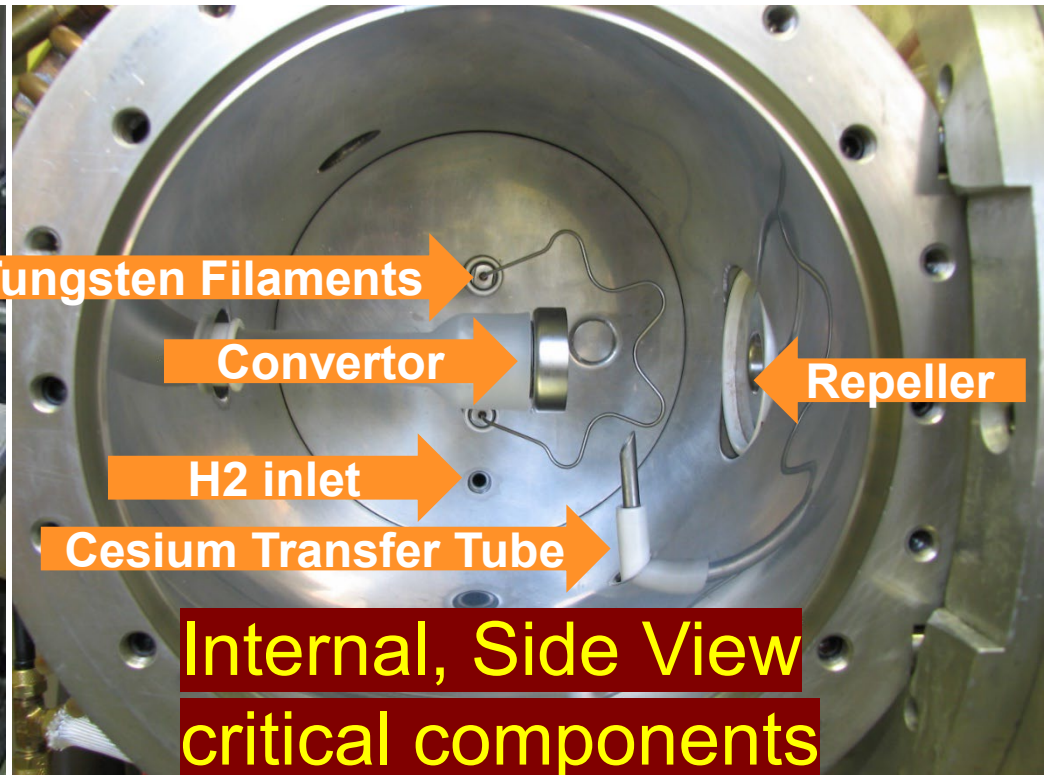
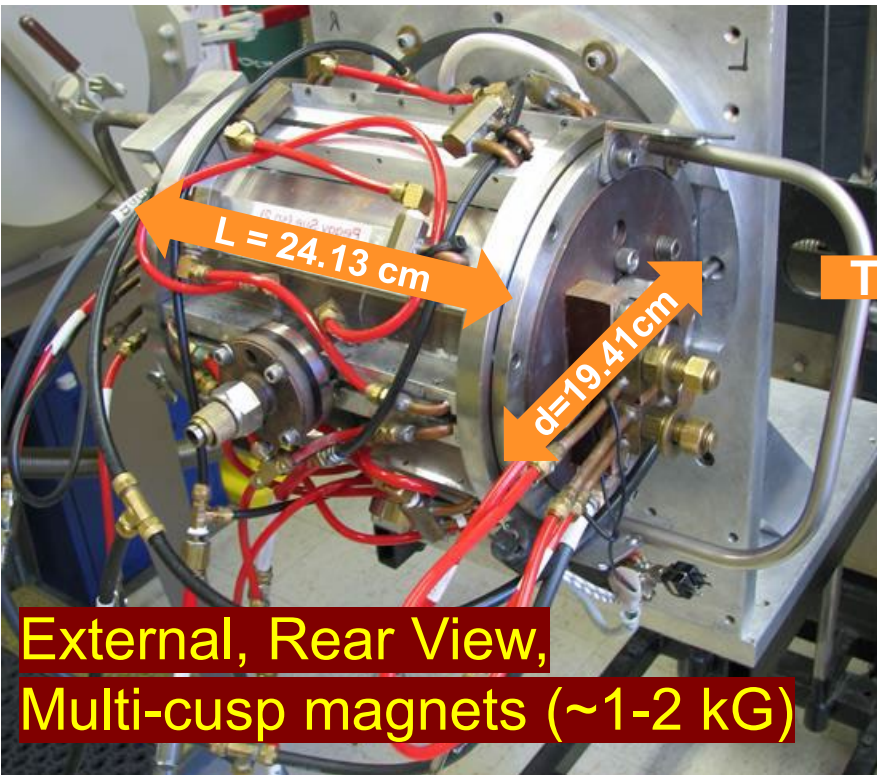
LANSCCE Front End Injection



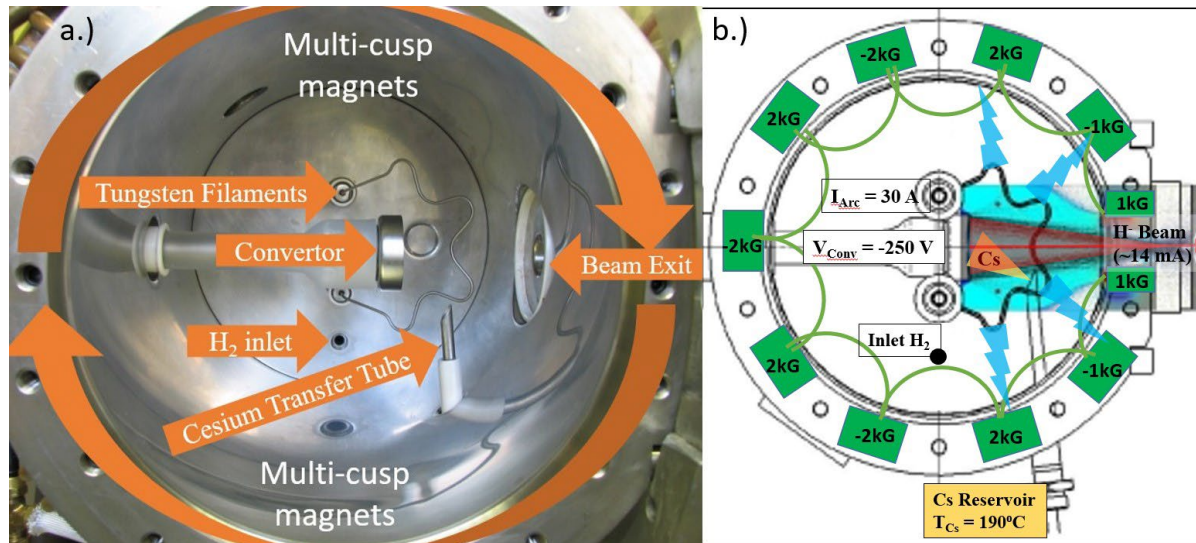
*Total current extracted from H- ion source
Is ~60-100mA, e-/H ratio about (3 to 5)/1*



The LANSCE Multi-cusp Cesiated Surface-Conversion H- Source: Photos

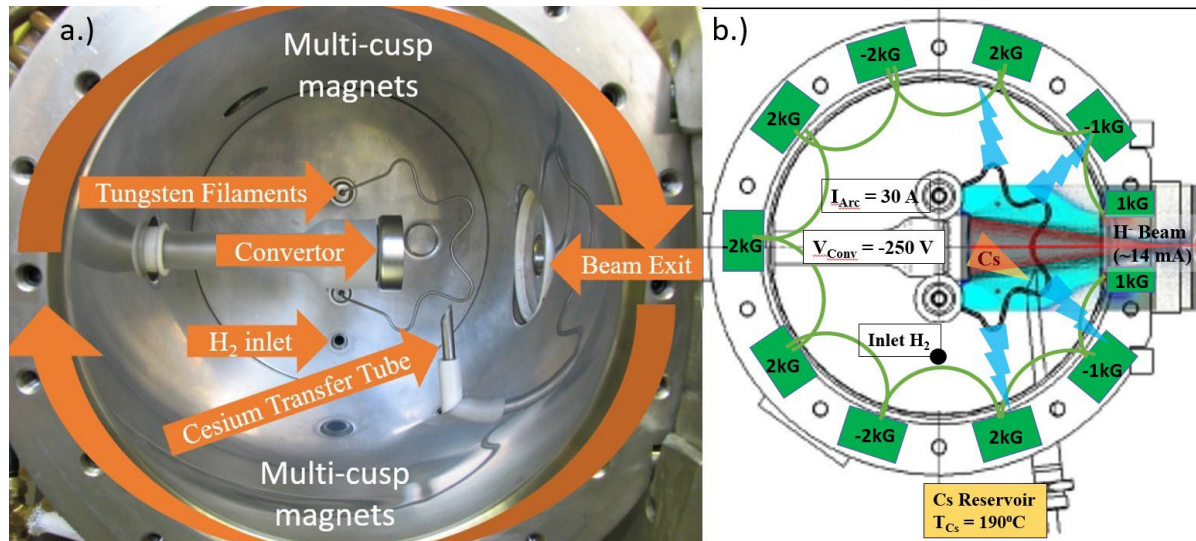


The LANSCE Multi-cusp Cesiumated Surface-Conversion H- Source: How H- Ion beam is made



- Vacuum chamber filled with *Hydrogen gas* (~ 1.0 mTorr).
- *Tungsten filaments* that provide a pulsed electron arc current that ionizes this H_2 gas and creates a plasma
 - (Pulse: 120 Hz, 1 ms on, 7 ms off) ($I_{DC} = 100$ A, $I_{arc} = \sim 30$ A)
- Plasma confined by a decagonal *multi-cusp magnetic* field in the walls.
- H^+ ions in the generated plasma are attracted to a negatively biased (-250 V) *converter*.
- The converter is coated in *cesium*. Low work function of *cesium* encourages surface-conversion of H_0 , H_x^+ to H^- ions.
- Negative Potential ejects produced H^- ions are promptly then ejected from the negative potential converter, which is concavely shaped to focus the **H- ion beam** towards the source exit and the high voltage beam injector (not shown).

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Motivation

- The internal process of Cs, H⁻ inside the source is not well understood
- Dynamic processes 10-1000 μ s scale
- **Cesium** surface-conversion is *the* vital ingredient for making H⁻ beam
 - Side effects lead to beam instabilities, e.g. beam injector arc downs
- The **H⁻ beam** creation, propagation, and neutralization inside the H⁻ ion source is not understood.
 - How and where are H⁻ ions created and destroyed? How many?

Motivation

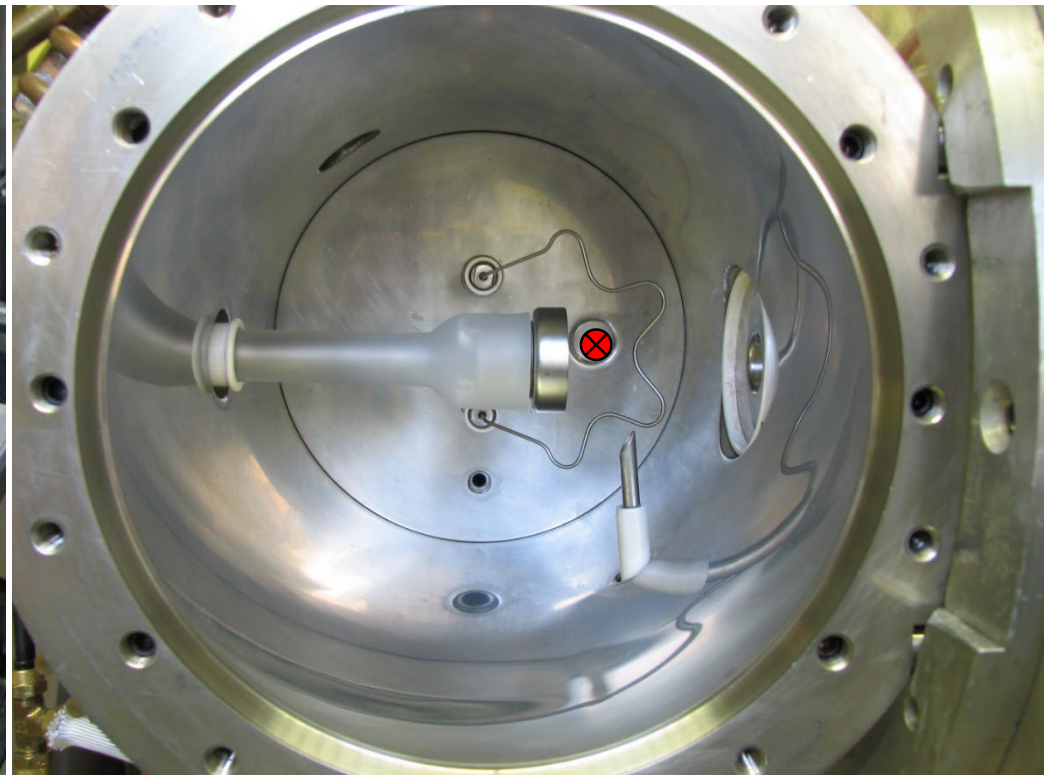
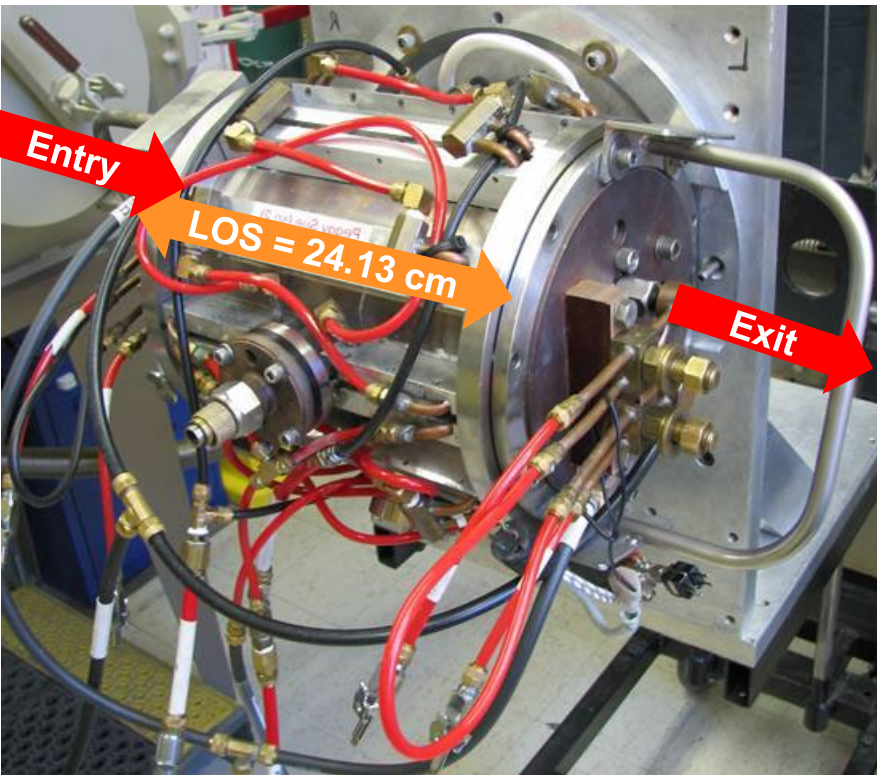
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 - **The correct tool is lasers tuned to atomic physics processes**
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Future progress requires an “H⁻ Ion Source Laser Diagnostic Stand”

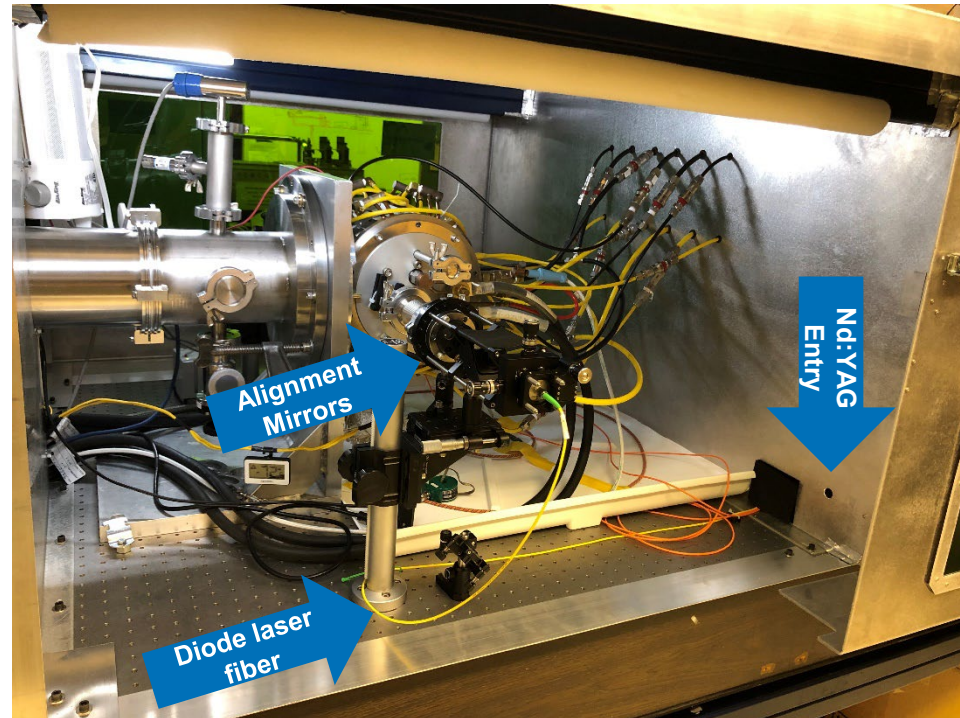
Proposed laser diagnostic path



- Just misses filaments
- Off slightly off center from Cs port
- Center of Converter H- Beam Path

Pics of Laser Diagnostic Stand

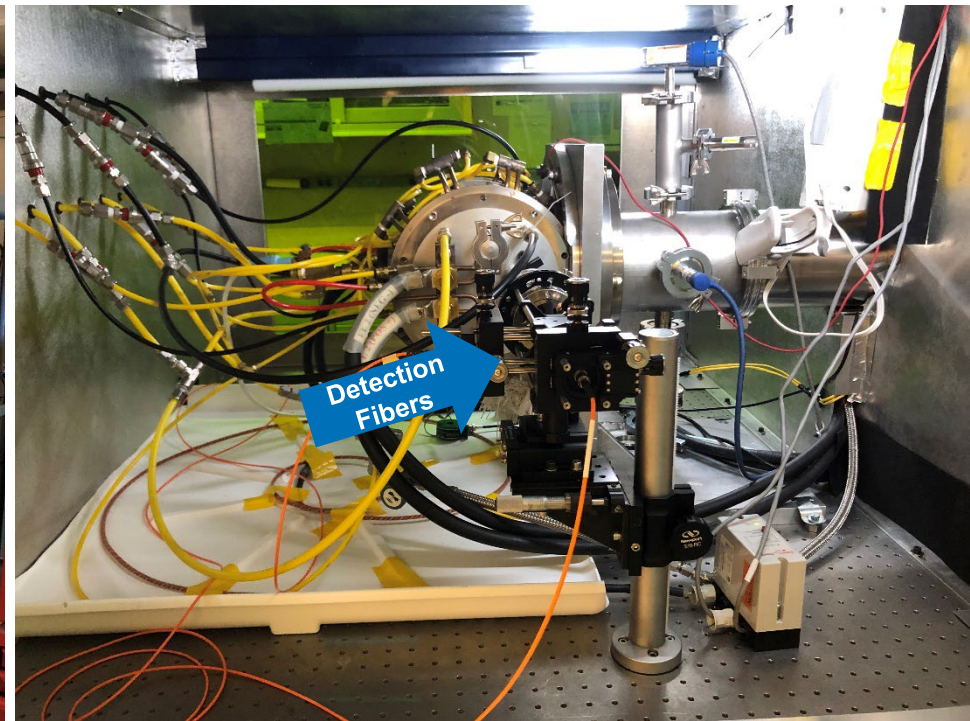
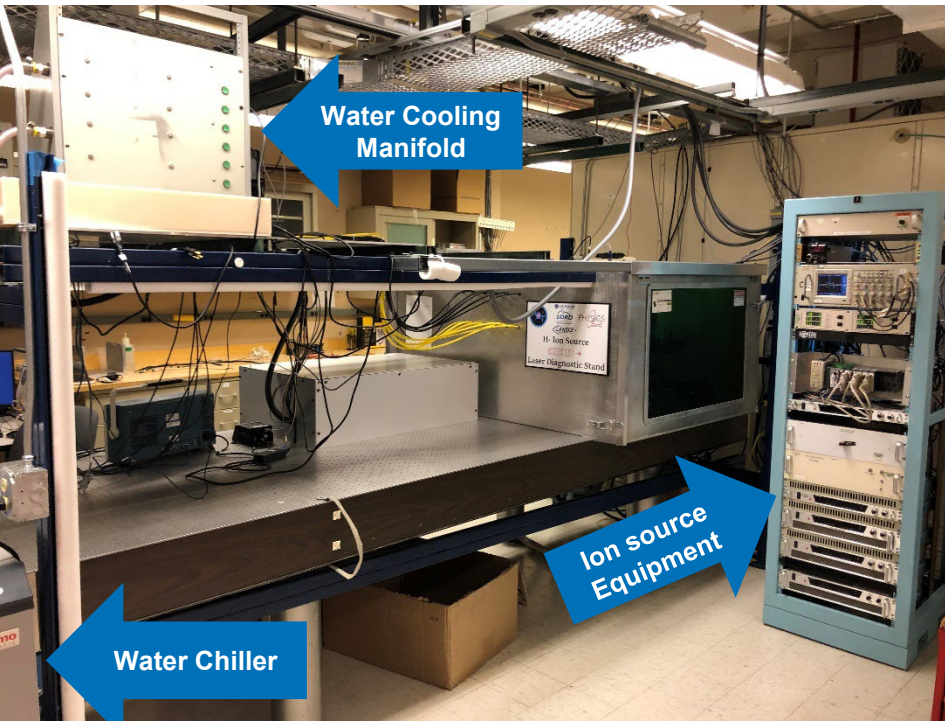
West Side



Diagnostic stand discussed at NIBS'2020
Fully built and functional!

Pics of Laser Diagnostic Stand

East Side

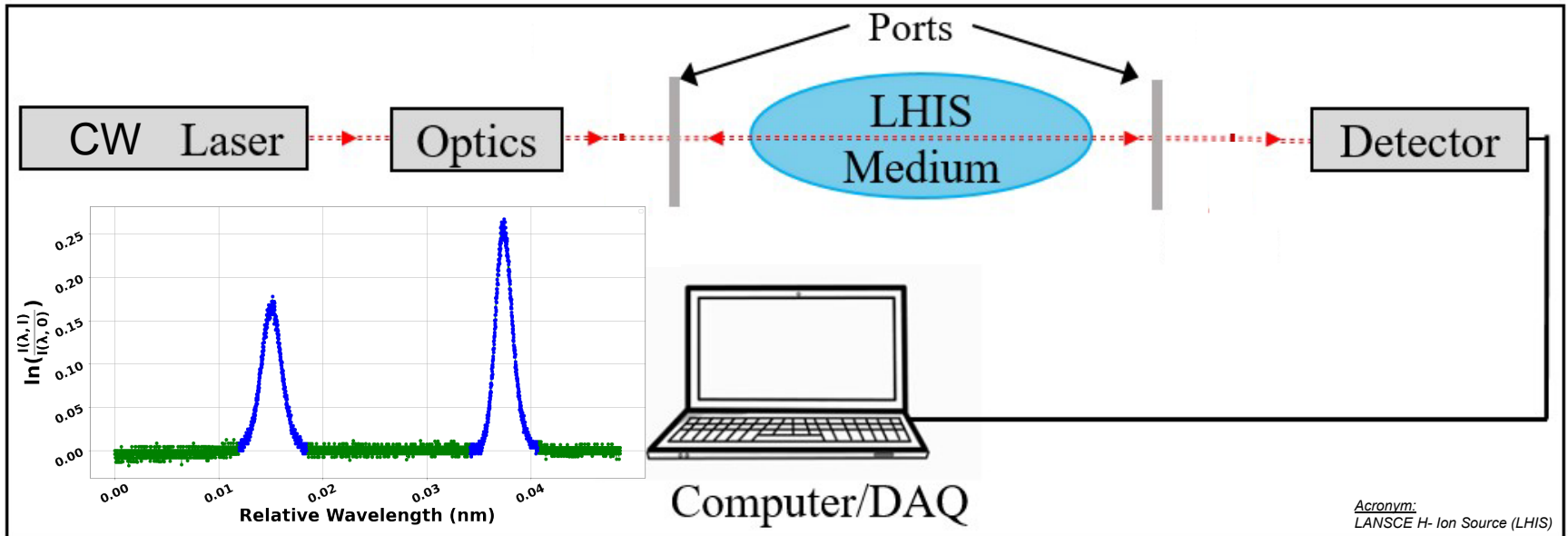


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Cs Measurements using TDLAS

- Experimental setup
- The measurements
 - *Dynamic* Cs Density measurements during H- Ion Source Pulse
 - *Static* Cs Density measurements just before H- Ion Source Pulse
 - Change various source parameters
 - *Unstable* Cs Density measurements
 - Goes by many names: Cesium Quench, Arc spike, Cesium burst
 - *Thermal* Cs measurements
 - 1st Estimation of T_{Cs}

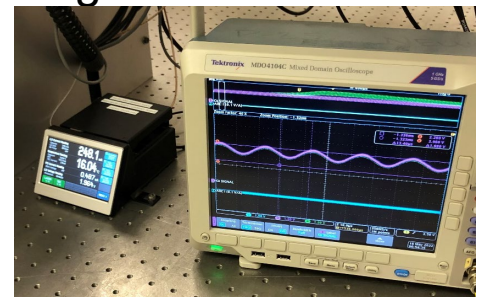
Optical setup block diagram. Resonant laser absorption for measuring Cesium Density



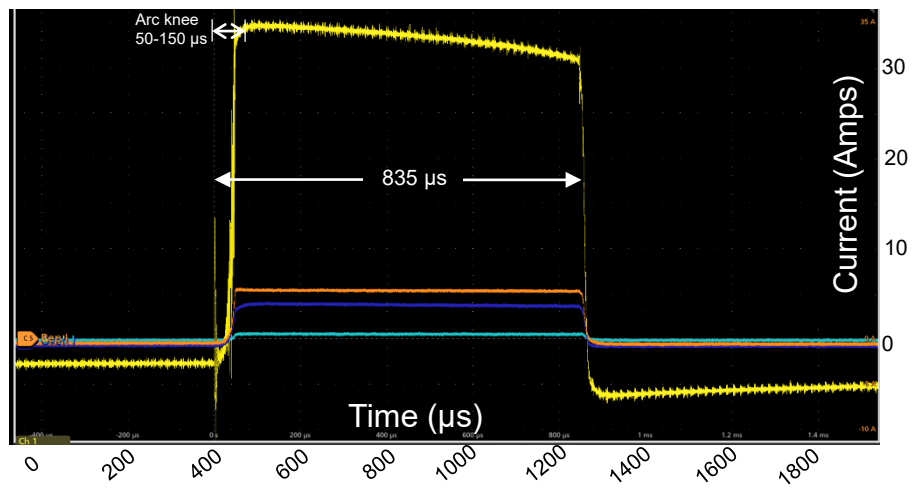
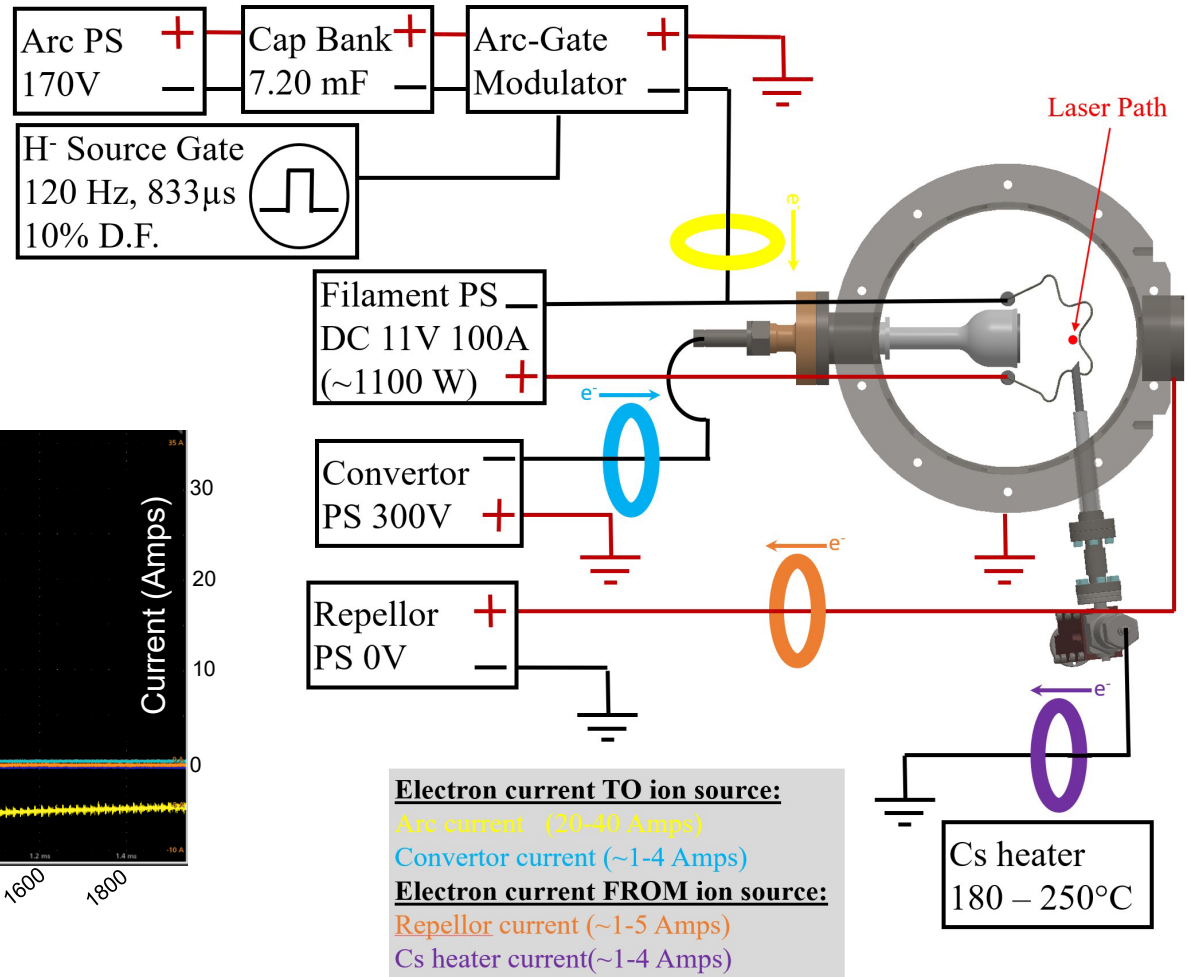
- A continuous, tunable diode laser is swept across an atomic transition (we use the D₂ transition, 6S_{1/2} → 6P_{3/2}, ~852 nm)
- Reference signal (not shown) is used for $\ln(\lambda, 0)$ instead of fitting

$$n_{Cs} = \frac{8\pi c}{\lambda_0^4} \frac{g_k}{g_i} \frac{1}{A_{ik} l} \int \ln\left(\frac{I(\lambda, l)}{I(\lambda, 0)}\right) d\lambda$$

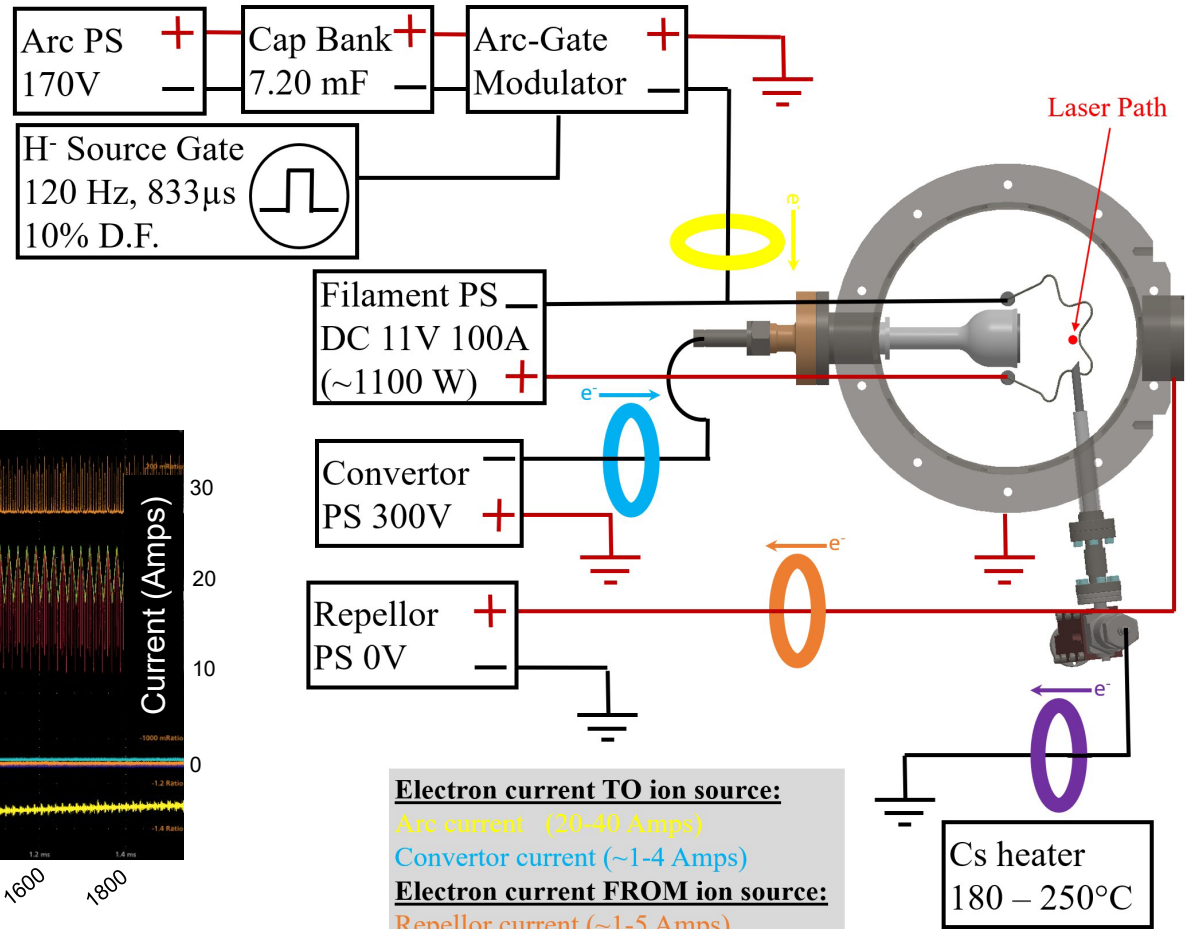
- Caveat: Depopulation effects not taken into account
 - Qualitative interpretation before quantitative



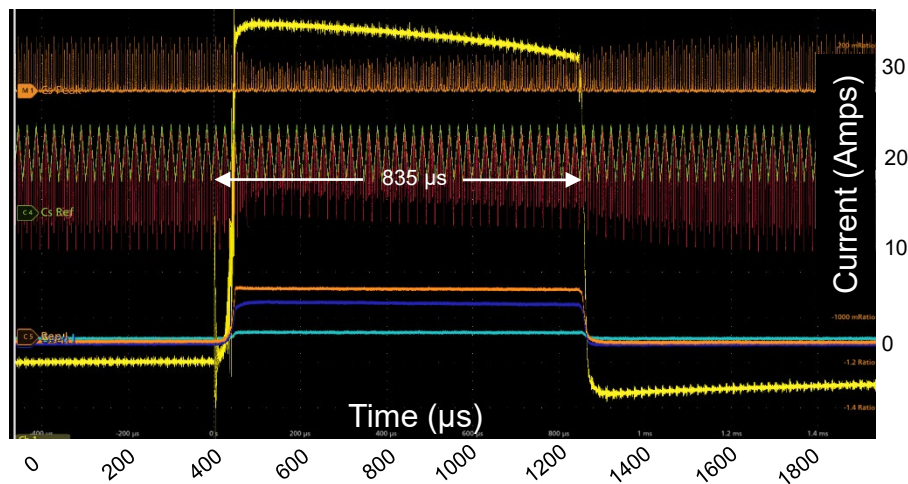
Relevant current measurements during ion source pulse



Relevant current measurements during ion source pulse With laser signal!



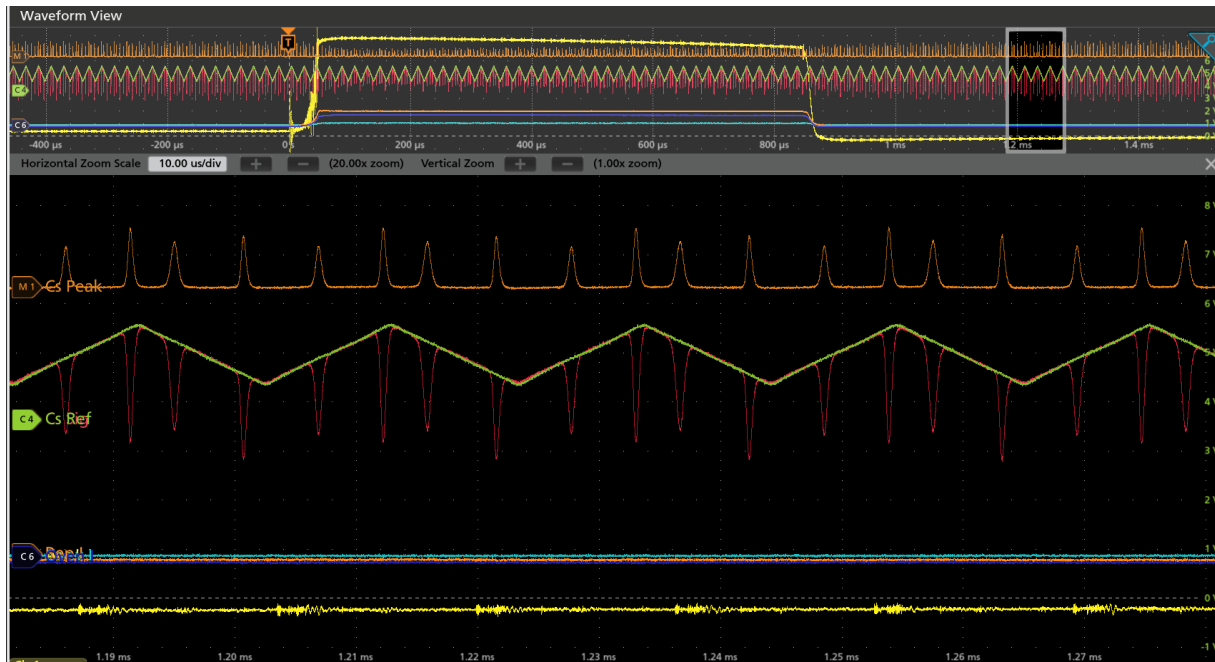
Apologies for the two “orange traces”!



Cs laser reference
Cs laser signal
-LN(Sig/Ref) (Upper Trace)

Electron current TO ion source:
Arc current (20-40 Amps)
Converter current (~1-4 Amps)
Electron current FROM ion source:
Repellor current (~1-5 Amps)
Cs heater current (~1-4 Amps)

Zoom in: Cs Density outside source pulse



- Cs Reference
- Cs Signal
- $-\ln(\text{Sig}/\text{Ref})$ (Upper Trace)
- Arc I
- Converter I
- Repeller I (Lower Trace)
- Cs Oven I

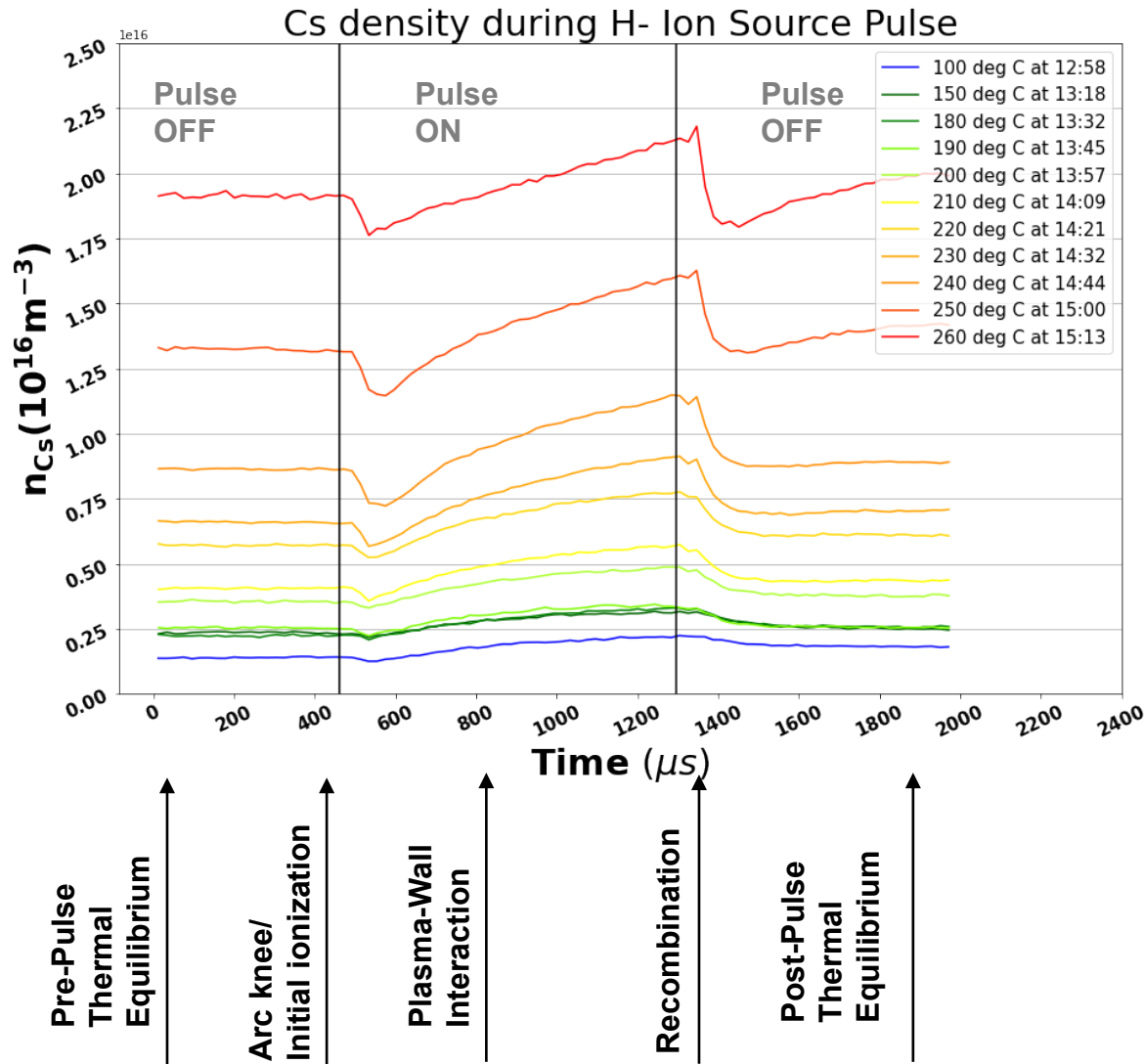
Zoom in: Cs Density outside source pulse

Cs peaks shorten and broaden inside the pulse compared to outside



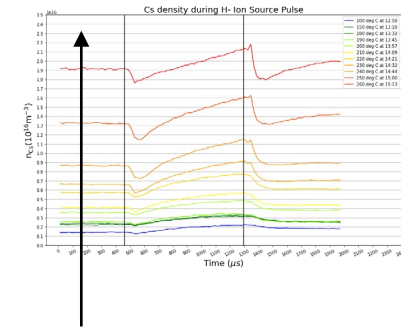
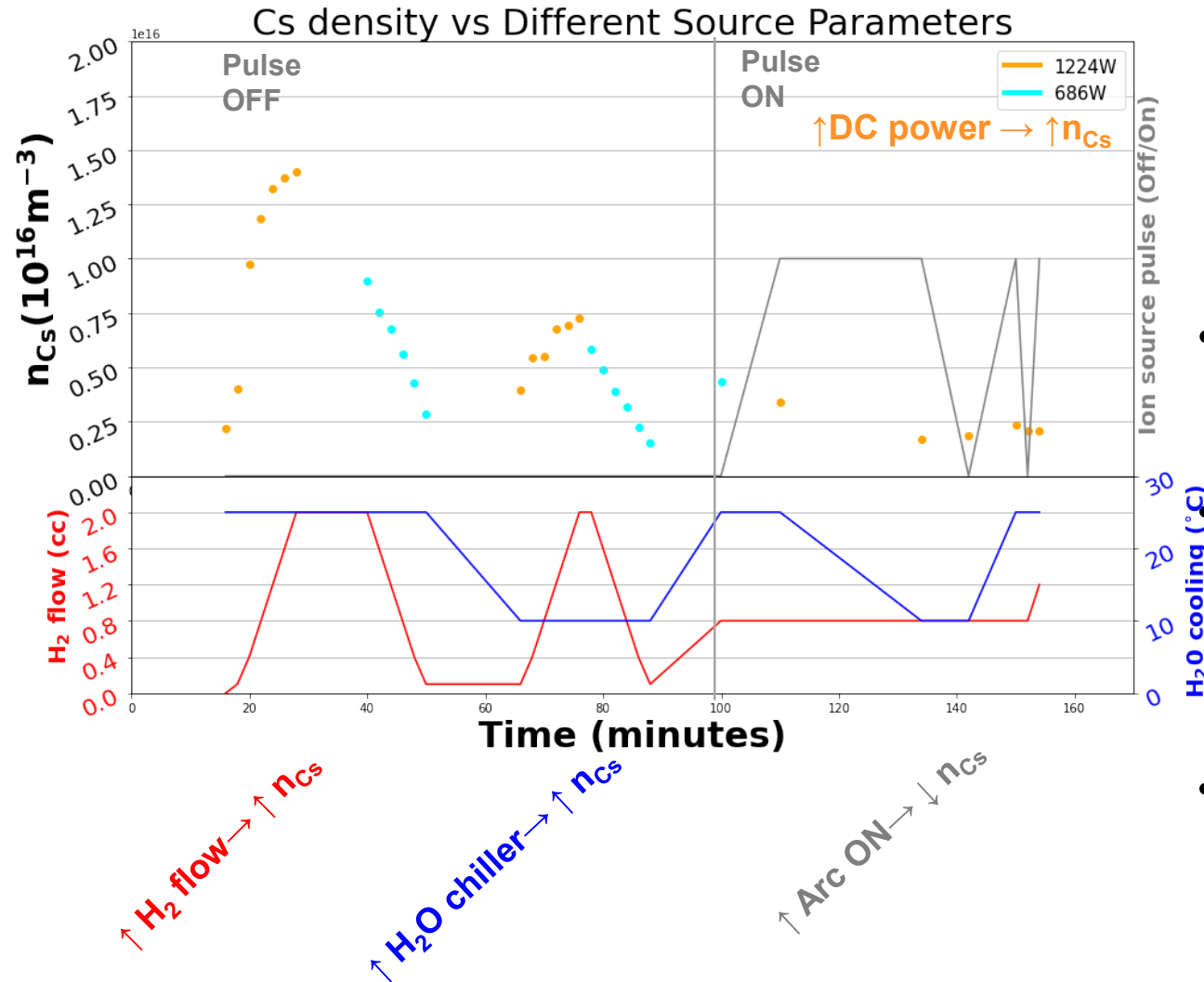
- Cs Reference
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Cs Density during an H- Beam Pulse



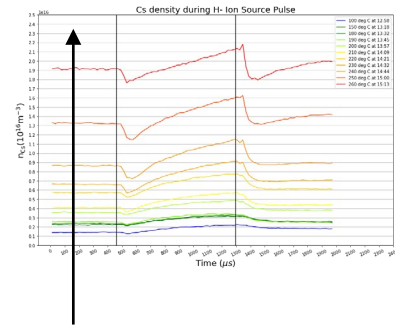
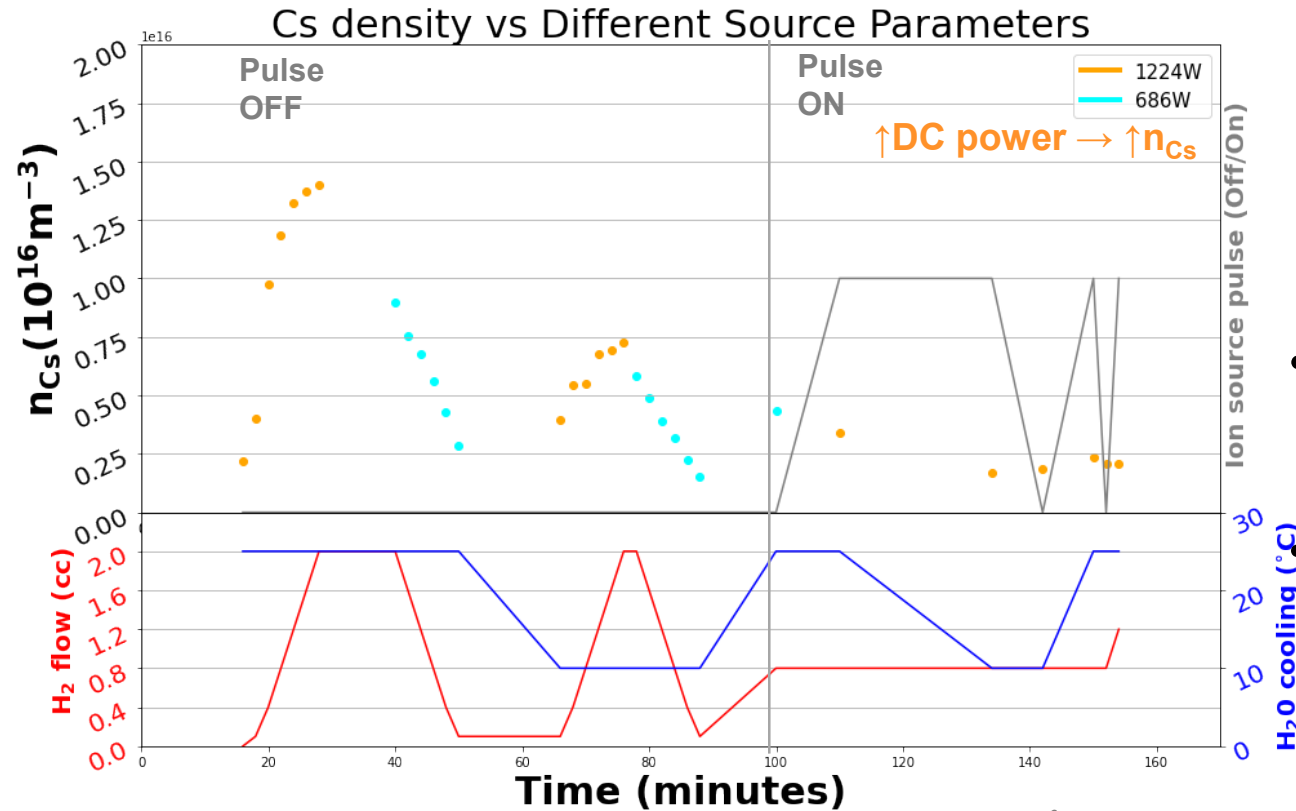
- Ion Source Fully running
- Adjust Cs Oven Temperature from 100°C to 260 °C
- Rate of Change in density as expected from Cs vs vapor pressure at ~1 mTorr.
- Cs during initial transfer is 250°C
- Nominal running ~180°C

Pre-Pulse Thermal Equilibrium Cs Density vs different Source Parameters



- **Cs Oven Temp OFF**
 - Relying on Cs already in the chamber
- **Pulse OFF (Static)**
 - Direct relationship to n_{Cs}
 - Filament Power
 - H₂ flow
 - H₂O chiller
- **Pulse ON (Dynamic)**
 - Inverse relationship to n_{Cs}
 - Suppression of n_{Cs} in LOS
 - Other effects less pronounced

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↑ H₂ flow → ↑ n_{Cs}

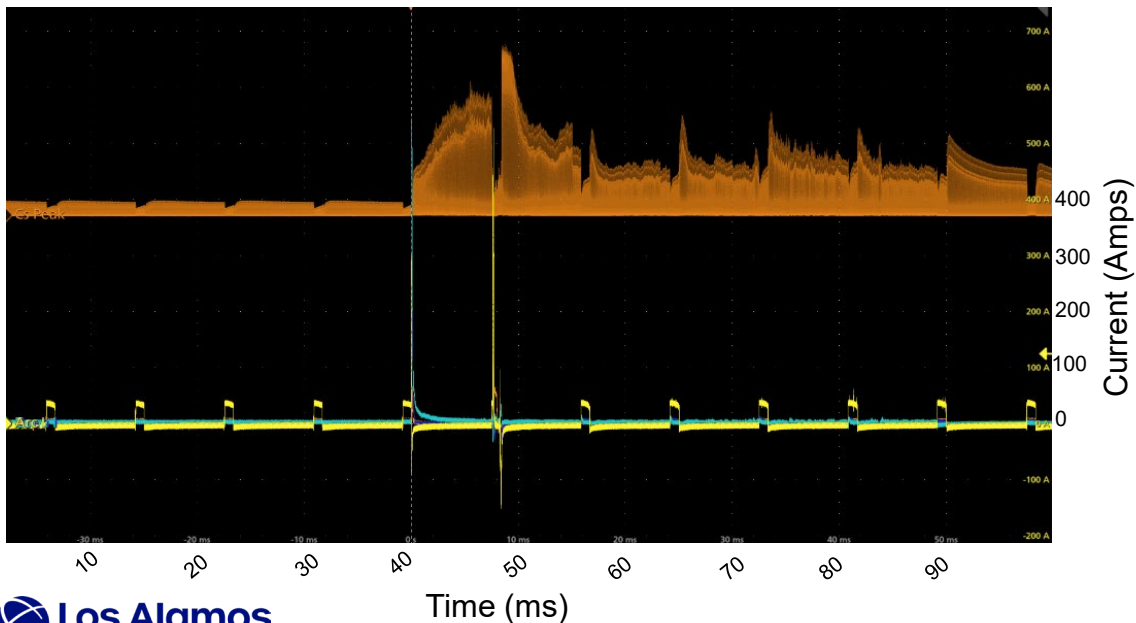
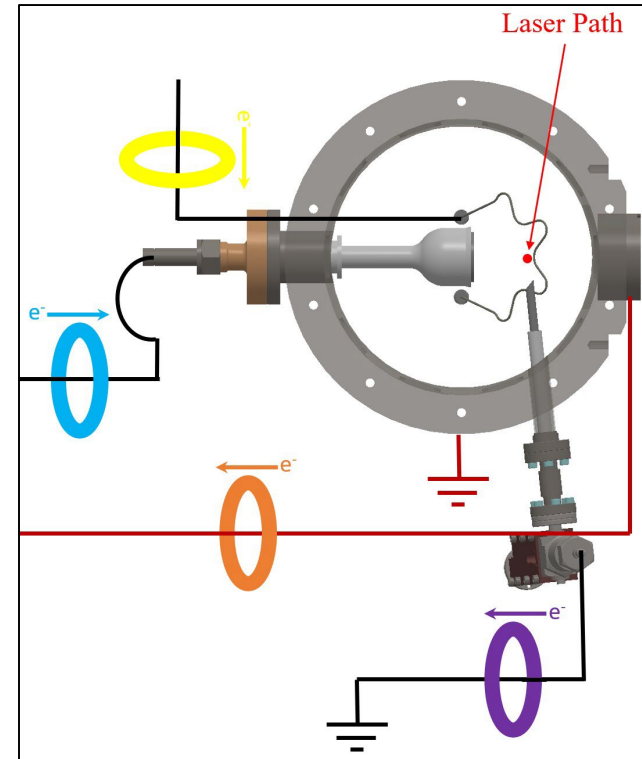
↑ H₂O chiller → ↑ n_{Cs}

↑ Arc ON → ↓ n_{Cs}

Continual Cs evaporation required to overcome this suppression

Ion source Cesiumated Quench and Spike studies

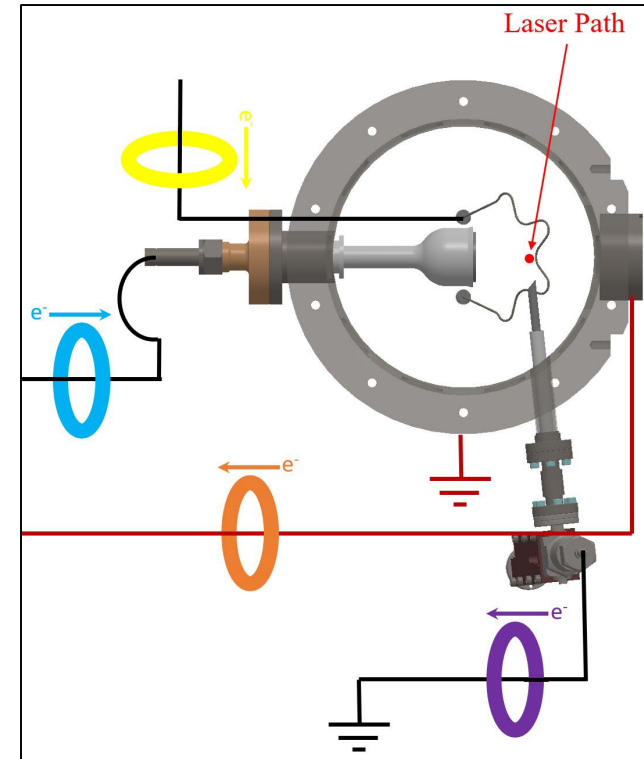
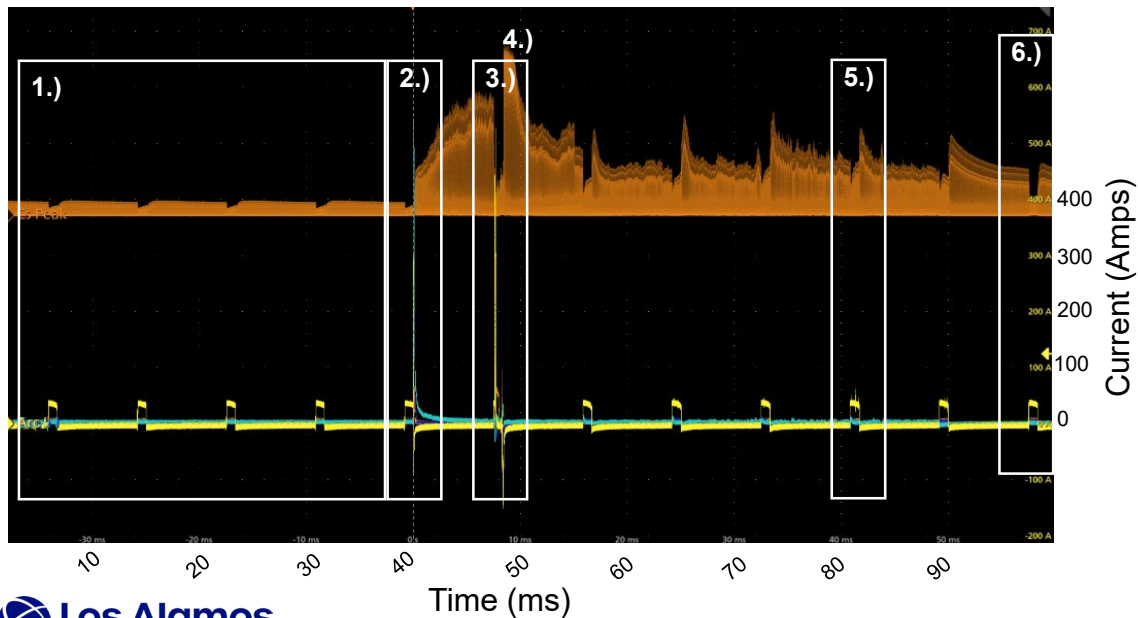
- Random cesiation effect cause instabilities on the Arc and/or Converter current in the Ion source.
 - Large → Arc/Converter Quench
 - Small → Arc/Converter Spike
- Cs laser perfect for studying this phenomena.
- At LANSCE, these cause beam instabilities
 - Arc down H- Ion Source 80 kV injector (1-5 per hour)
- *What follows: many qualitative plots of one of these events (Below)*



-LN(Sig/Ref) (upper trace)
 Arc I
 Converter I
 Repeller I (lower trace)
 Cs Oven I

Ion source Cesiumated Quench and Spike studies

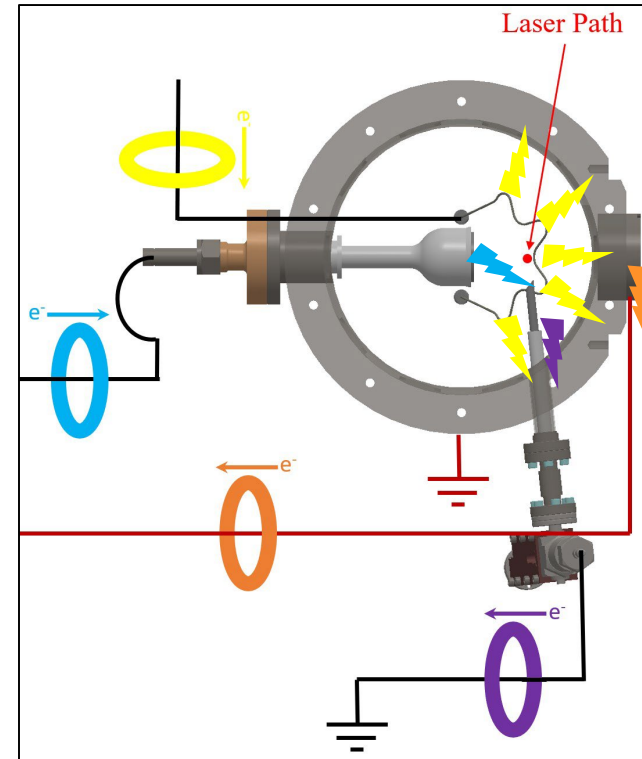
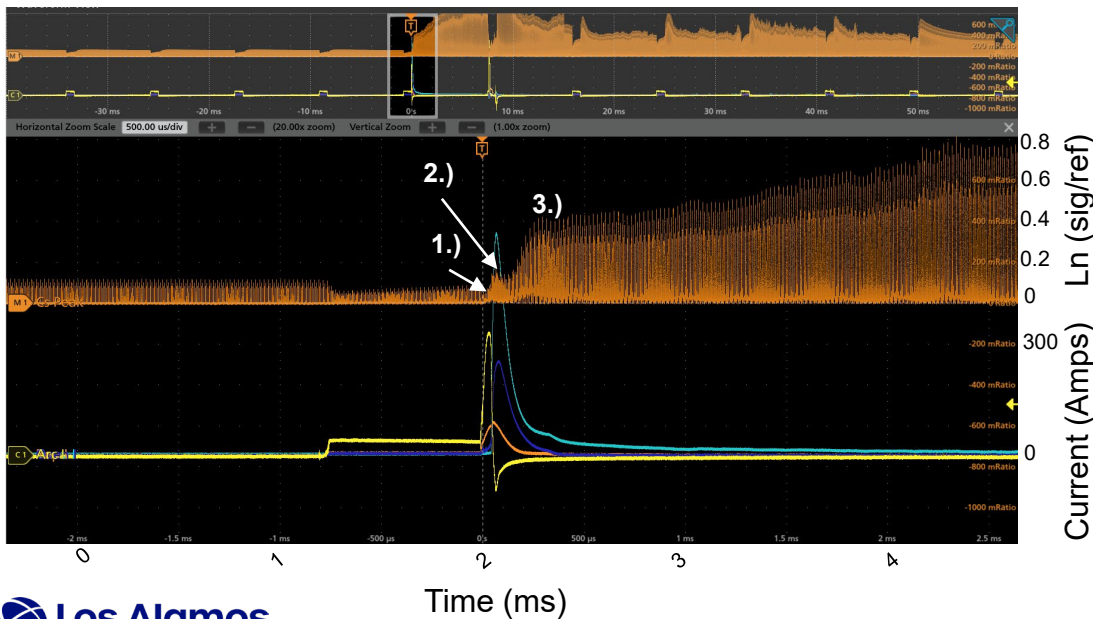
- 1.) Nominal pulses
- 2.) 1st Cesiumated Quench
- 3.) 2nd Cesiumated Quench
- 4.) Line Saturation
- 5.) Arc Spikes
- 6.) Slow return to nominal?



-LN(Sig/Ref) (upper trace)
 Arc I
 Converter I
 Repeller I (lower trace)
 Cs Oven I

1st Cesiated Quench

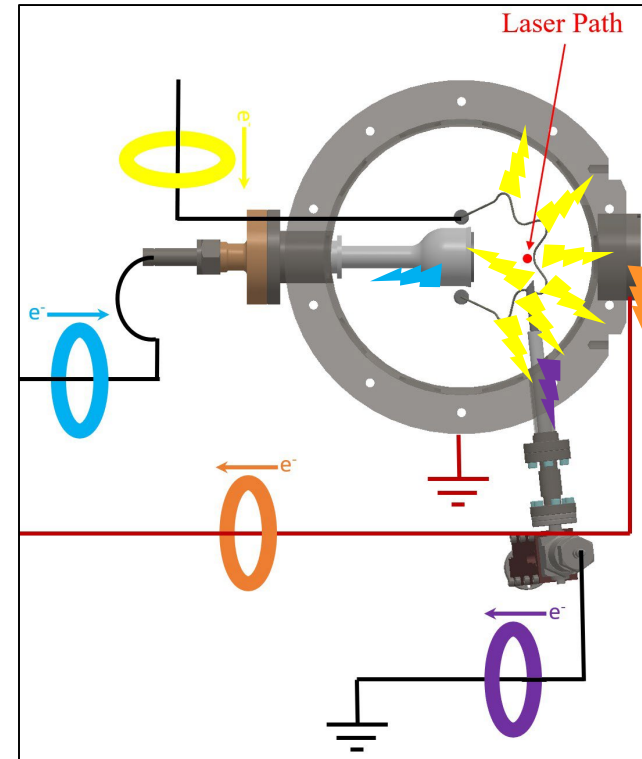
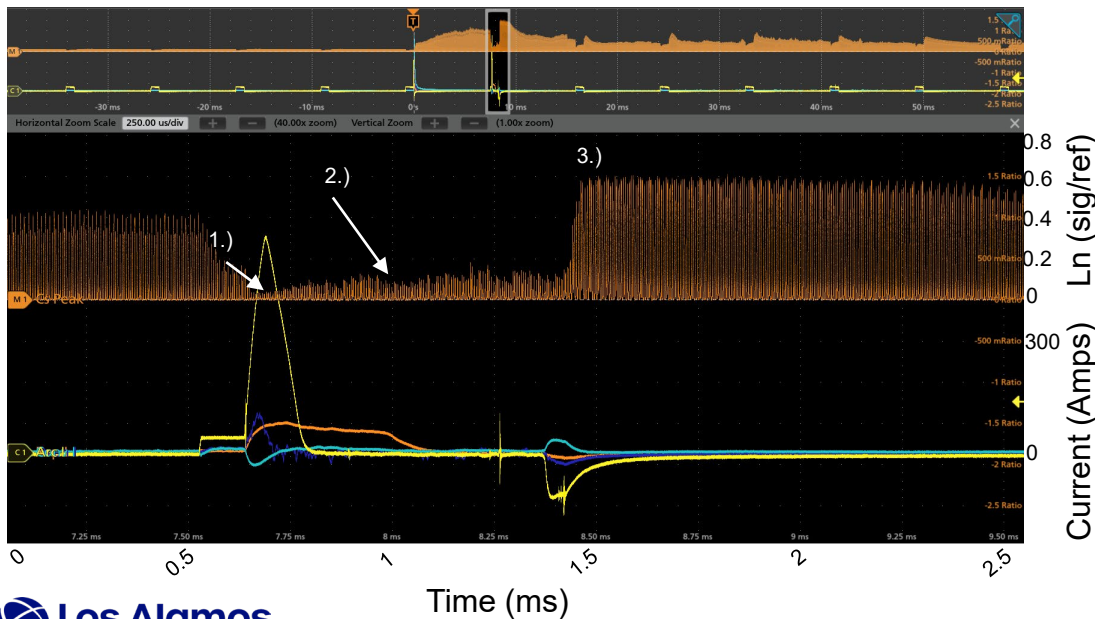
- **Arc current** appears to shorted, goes everywhere
 - Partially to the **Repeller**
- **Converter** then Arcs to **Cs Oven**
- 1.) Brief decrease onset of Arc Current
- 2.) Brief increase onset of Converter Current
- 3.) Cs everywhere after pulse off!



-LN(Sig/Ref) (upper trace)
 Arc I
 Converter I
 Repeller I (lower trace)
 Cs Oven I

2nd Cesium Quench

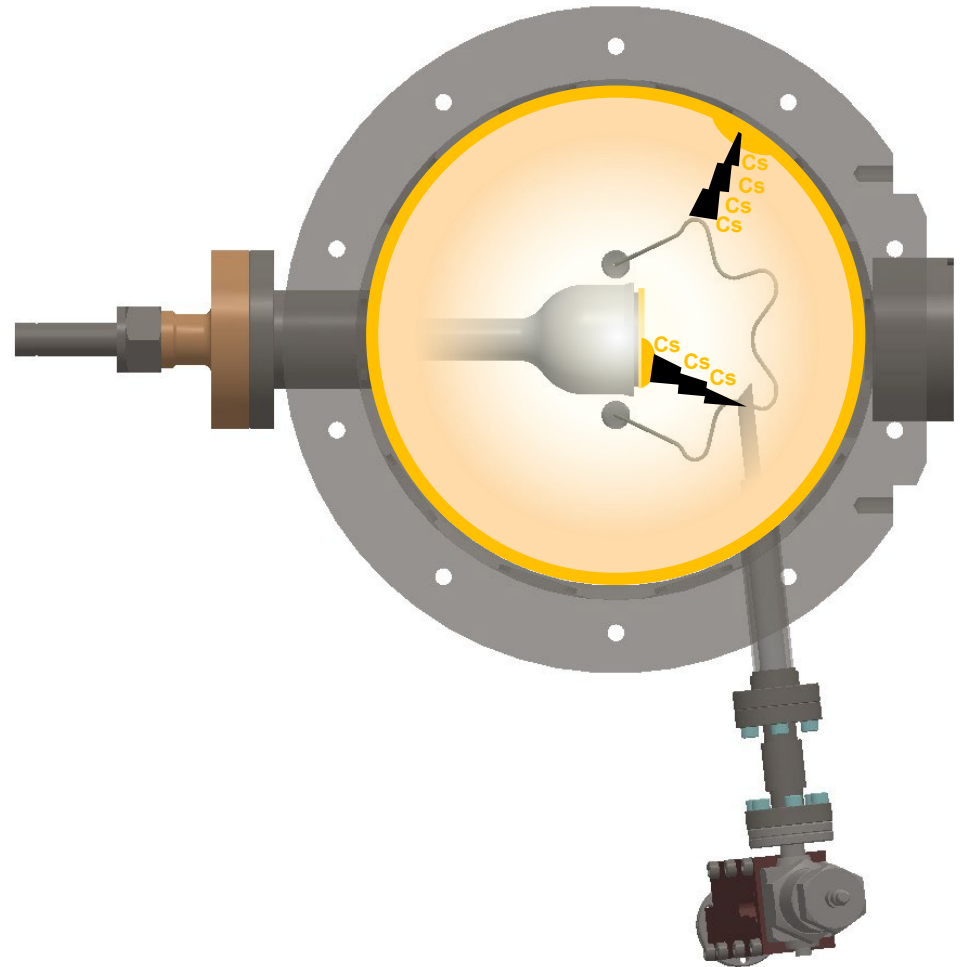
- **Arc current** appears to shorted, goes everywhere
 - Partially to the **Repeller**
 - Partially to the **Cs Oven**
 - Partially to the **Converter**
- 1.) Brief decrease onset of Arc Current
- 2.) Plasma-Wall interactions
- 3.) Cs everywhere after pulse off!



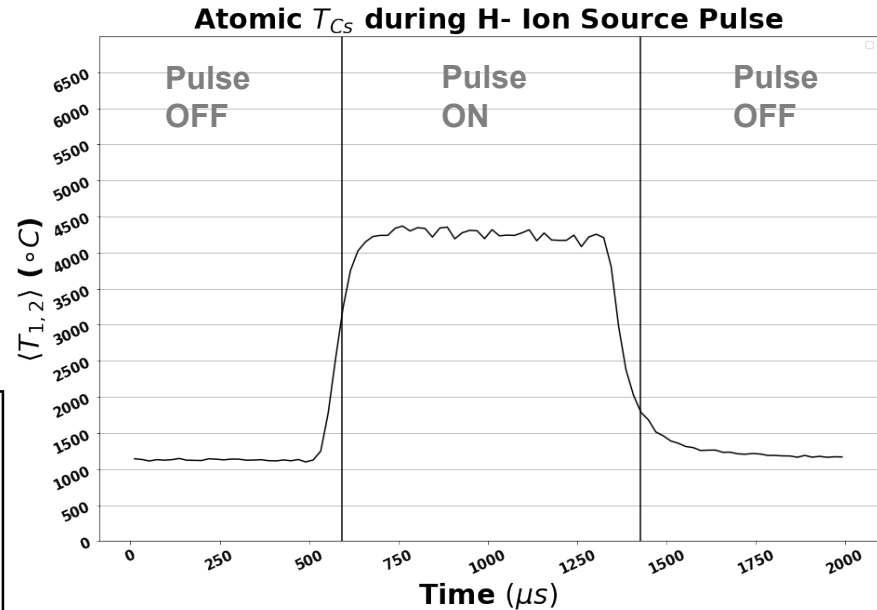
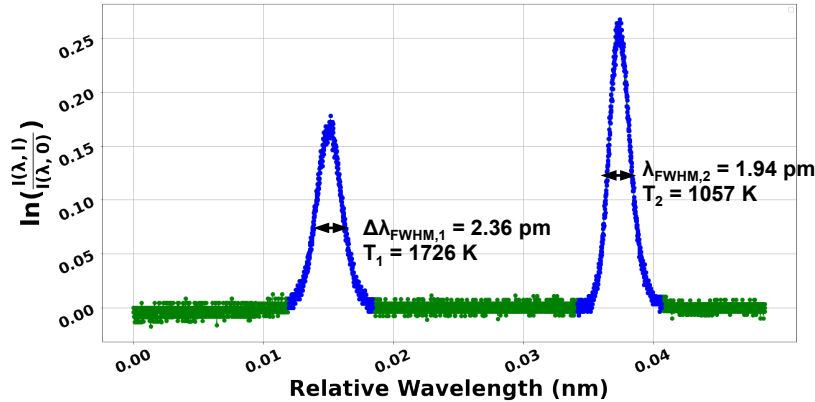
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 Arc I
 Converter I
 Repeller I (lower trace)
 Cs Oven I

What causes these Cesium quenches?

- Nonuniform **Cs deposits** that build up on walls/converter?
- Nonuniform **Evaporative** effects?
 - Creates conductive plasma?
- **Path to Ground** Created somehow
 - Non-neutral plasma?
 - Instantaneous **“paschen follies”**?
- More Quenches seen when turning on cold source
 - Non-uniform Cold Cs deposits



First look at Cs Temperature during an H- Beam Pulse



$$\Delta\lambda_d(T_{Cs}) = 2 \frac{\lambda_0}{c} \sqrt{\frac{2 \ln(2) k_B T_{Cs}}{m}}$$

$$T_1(\Delta\lambda_{\text{FWHM},1}) = -300 + 29 \cdot \Delta\lambda_{\text{FWHM},1}/\text{pm} + 350 \cdot (\Delta\lambda_{\text{FWHM},1}/\text{pm})^2,$$

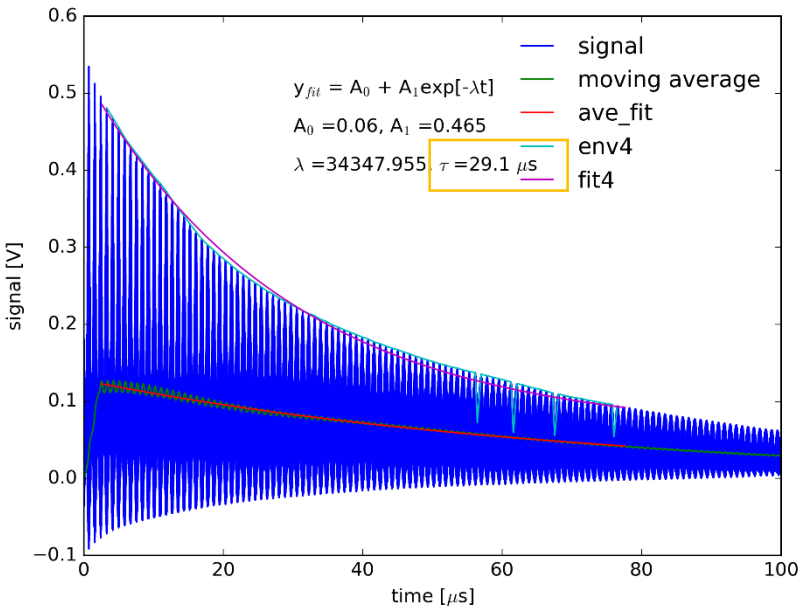
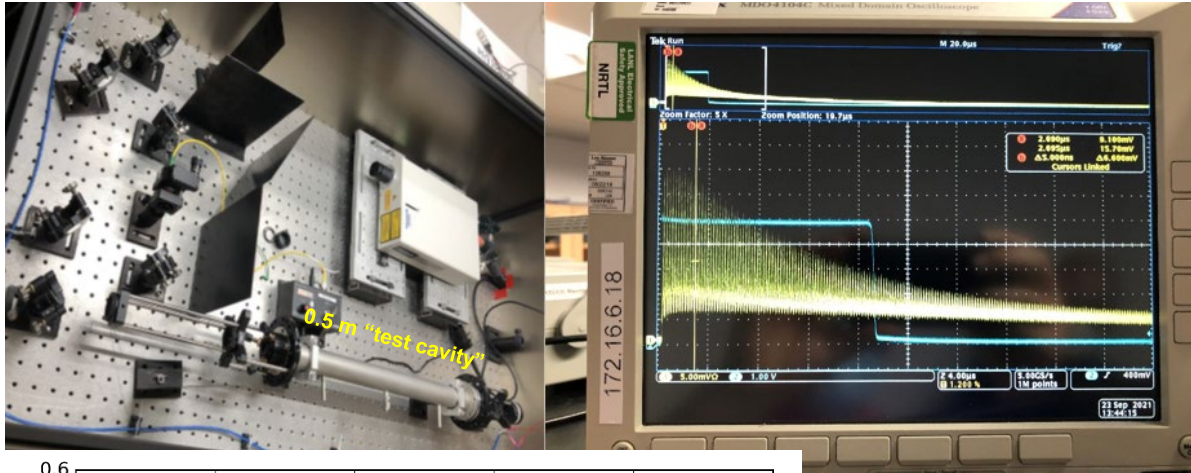
$$T_2(\Delta\lambda_{\text{FWHM},2}) = -300 + 1.7 \cdot \Delta\lambda_{\text{FWHM},2}/\text{pm} + 360 \cdot (\Delta\lambda_{\text{FWHM},2}/\text{pm})^2.$$

M. Lindaur, Master Thesis, Univ. Augsburg (2017)

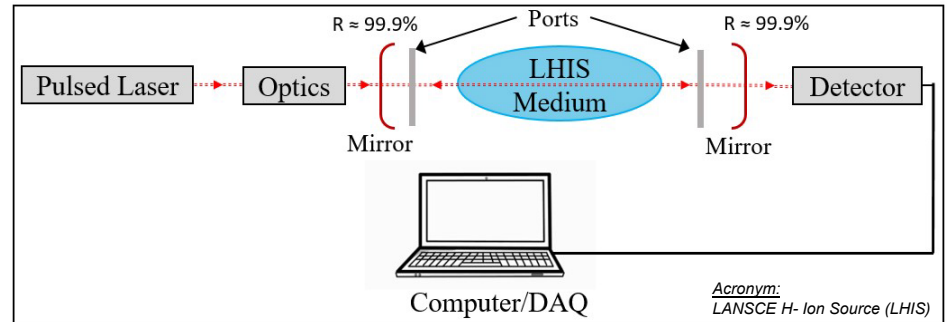
- **Pulse OFF** temp ($\sim 1200^{\circ}\text{C}$) is similar to the in-house *emissivity* measurements of filament DC temperature ($\sim 1700^{\circ}\text{C}$)
- Work ongoing to determine to proper accuracy

H- Density Measurements using CRDS

Test cavity

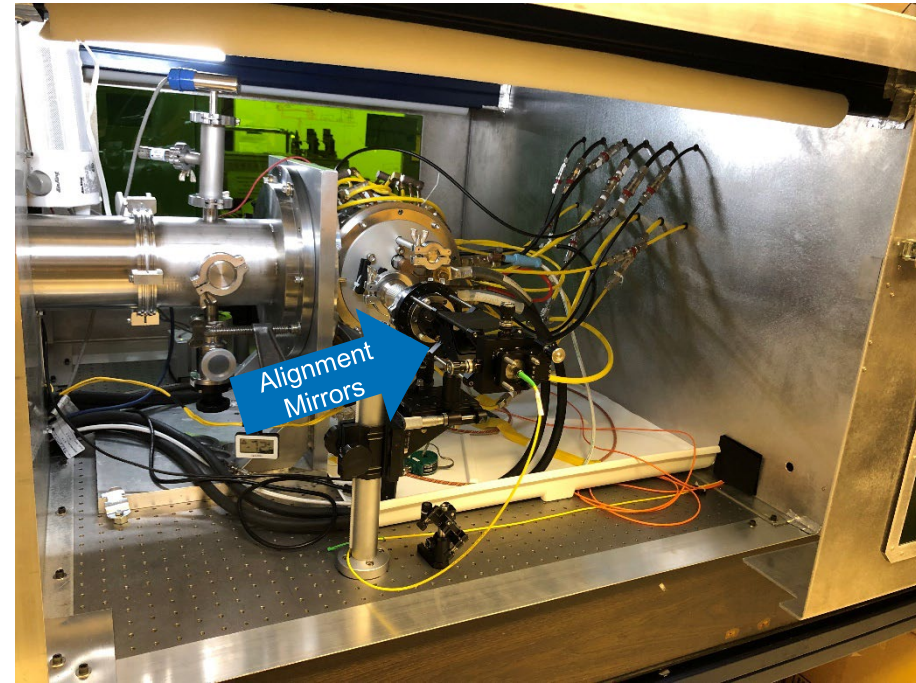
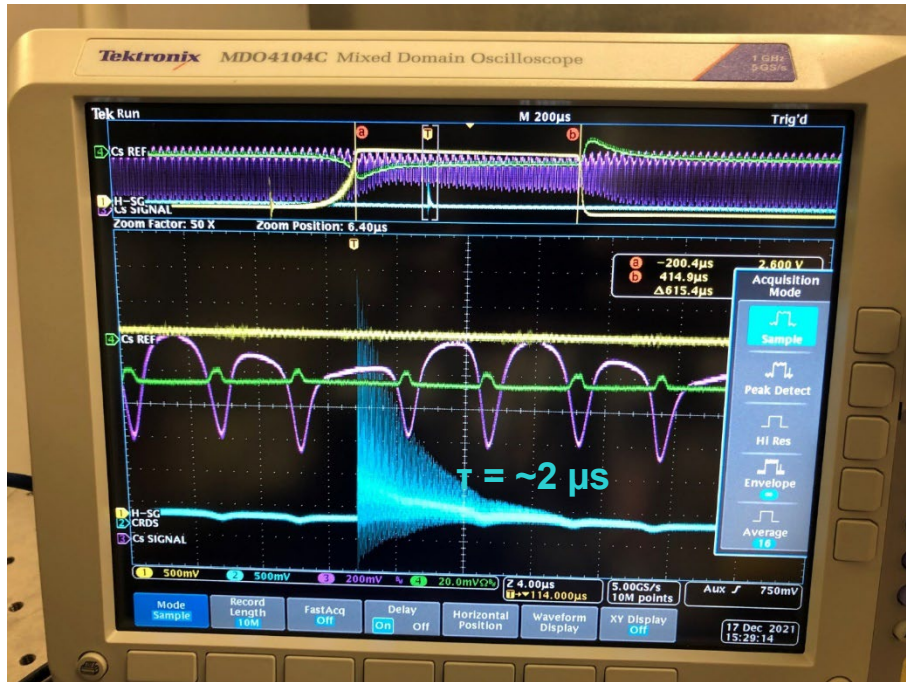


- 29 μs during test. (~0.5 m cavity length)
- Achieved good characterization of CRDS



H- Density Measurements using CRDS

H- Ion Source



- Decay only $2 \mu\text{s}$, vs $26 \mu\text{s}$ during test. ($\sim 0.8 \text{ m}$ cavity length)
- Issue: Need to Improve alignment mirror manifold
 - Atmosphere vs vacuum alignment. Slight skew between east/west optical ports.
- Issue: Decay became shorter over time
 - Mechanical vibration/thermal issues?
 - Mirror contamination

Conclusions

- Fully developed H- Ion Source Laser Diagnostic Stand
 - 1st results of Cs TDLAS measurements shown
 - Stay tuned for H- measurements



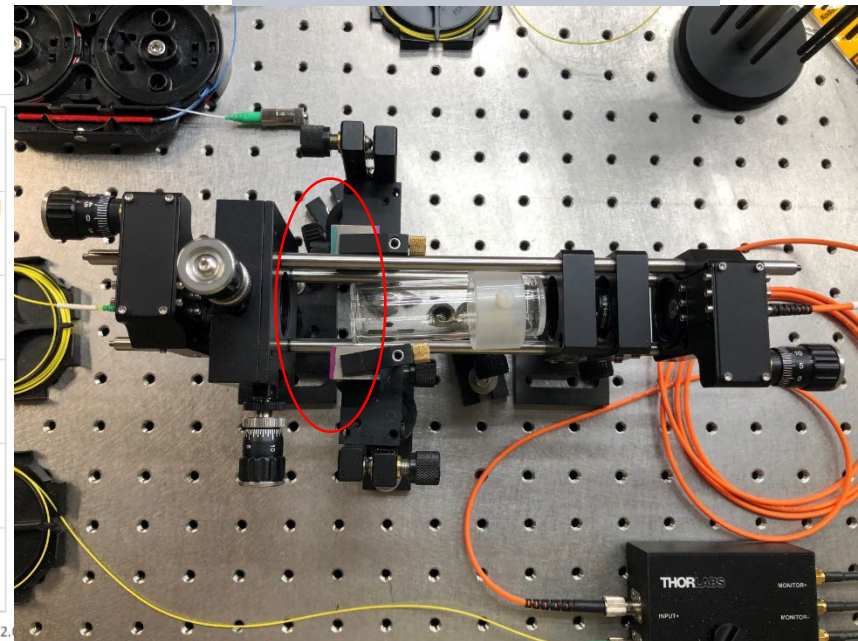
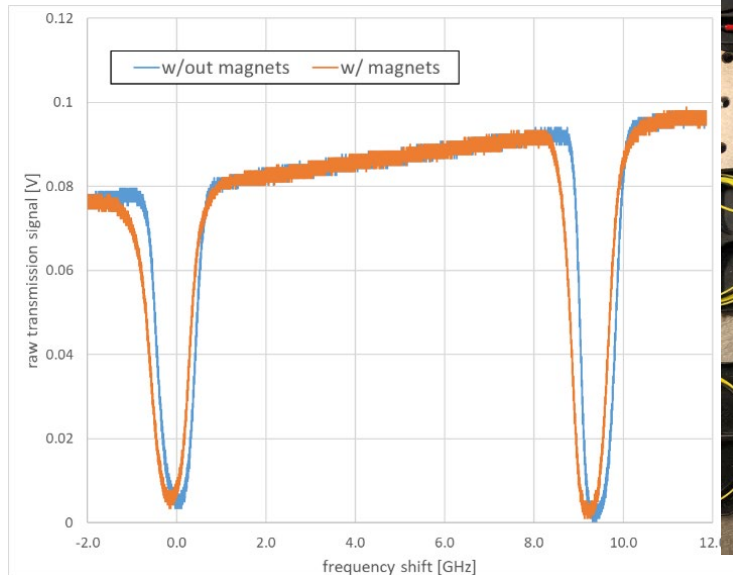
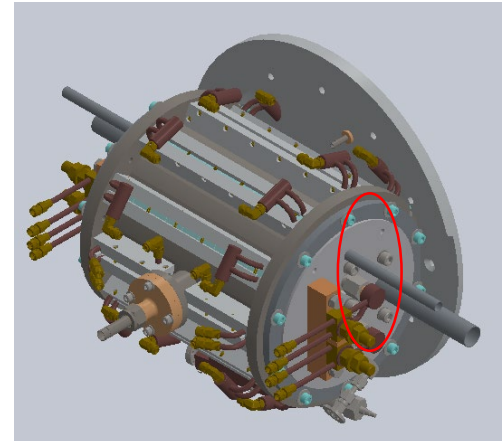
Acknowledgements

- We are grateful to collaborators at the Max Planck Institute for Plasma Physics –Garching
 - Ursel Fantz, the ITED division leader at IPP Garching
 - Bernd Heinemann, NBI group leader
 - Dirk Wunderlich, experimental leader of the ELISE test facility
 - *Special Thanks*
 - Christian Wimmer, experimental leader at BATMAN Upgrade test facility
 - Alessandro Mimo, CRDS, TDLAS expert at BATMAN and ELISE
- We are grateful to our funding agencies:
 - LANL LDRD Office
 - The Department of Energy, and the National Nuclear Security Administration for supporting our work.

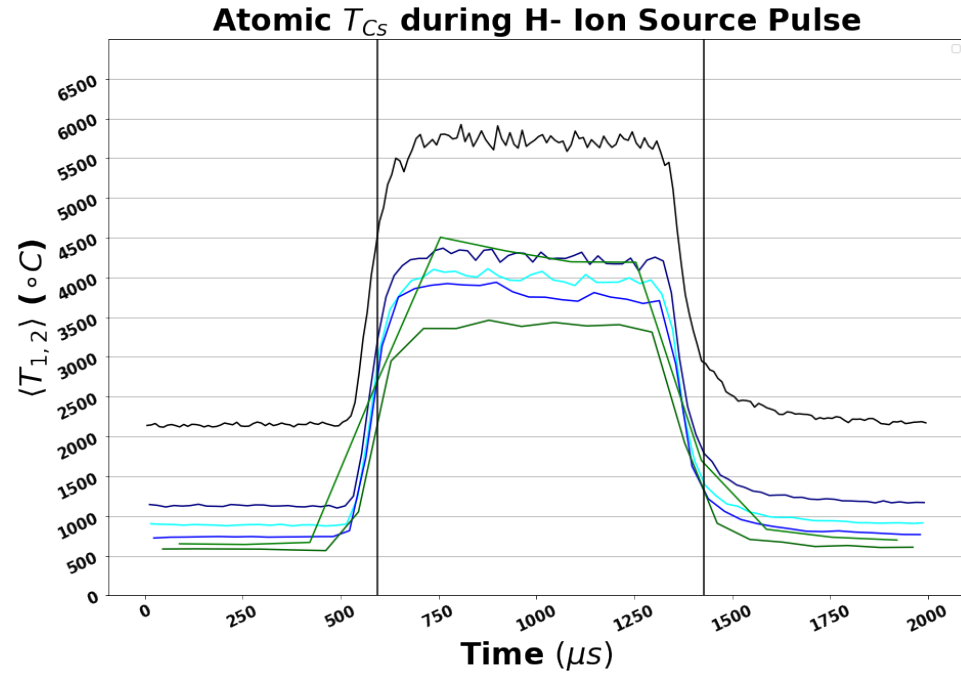
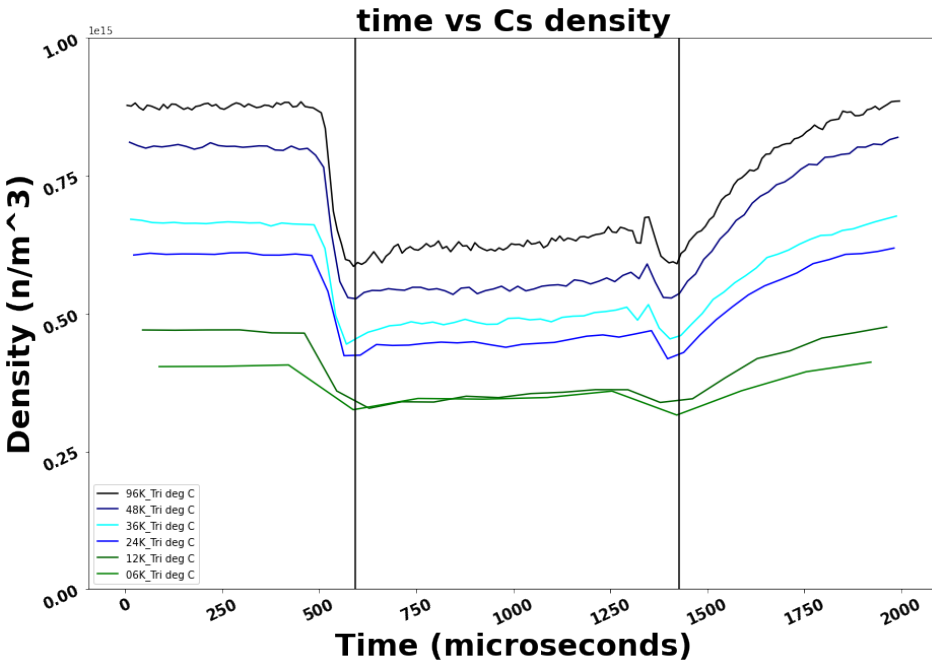
Backup

Checking for Magnetic Effects

- Magnetic field strongest by the walls.
- Will magnetic field at entry/exit cause Zeeman splitting?
- The effect is negligible/manageable
 - 2kG magnets tested in lab
 - 1kG in source
- No mag: 5.61×10^{16} atoms/m³
- With mag: 5.94×10^{16} atoms/m³
→ 6% difference. **NOT AN ISSUE**



Density & temp vs freq



The LANSCE Multi-cusp Cesiated Surface-Conversion Source with initial 80 kV extraction

Total current extracted from H- ion source
 $I_s \sim 60\text{-}100\text{mA}$, e^-/H^- ratio about (3 to 5)/1

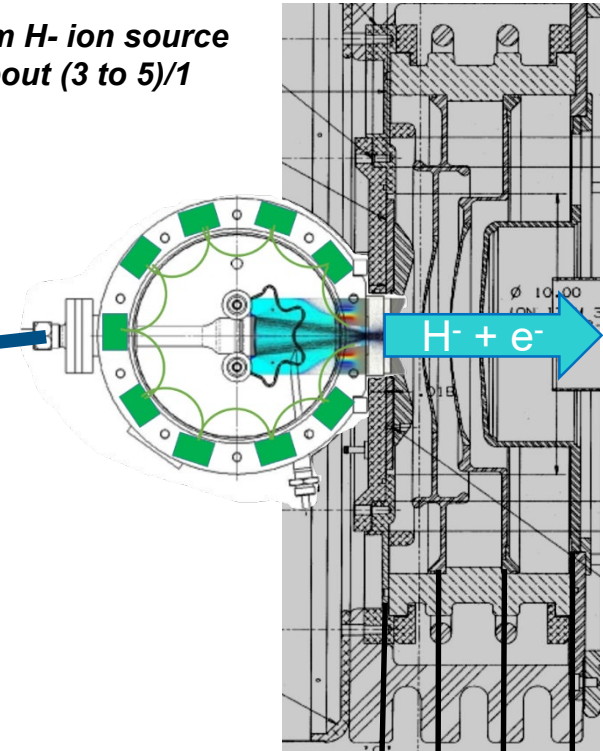
Ion source
Equipment
Racks:

Hydrogen flow
Filament PS
Converter PS
Cs oven ctrl
Etc.

Floating at
80kV

80 kV
Supply/Regula
tor

Cables to
Ion Source



Ion Source: -80 kV

Extractor: -68 kV

Column: -28 kV

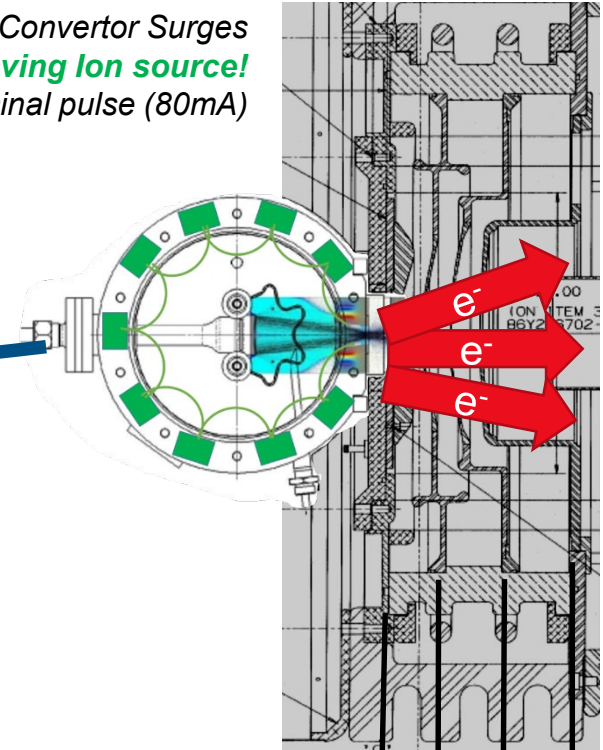
Ground: 0V

Large Transient observed with 80kV (June 2019)

~500 Amp Arc, Converter Surges
 ~1 Amp of Charge leaving Ion source!
 20x the charge during nominal pulse (80mA)

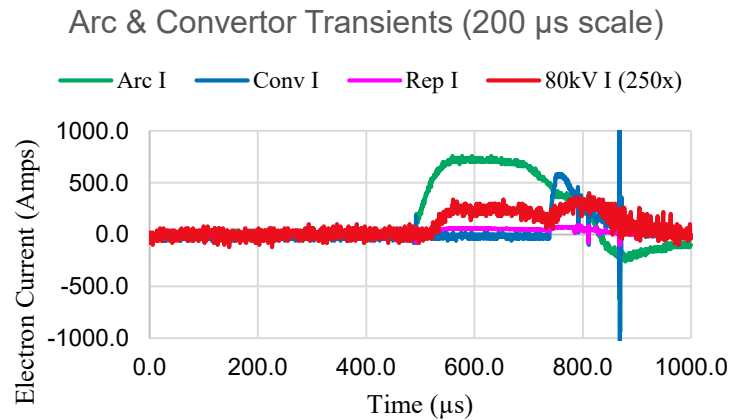
Ion source
 Equipment
 Racks
 Floating at
 80kV

Cables to
 Ion Source



Ion Source: -80 kV
Extractor: -68 kV
Column: -28 kV
Ground: 0V

No wonder the 80kV Arcs Down



80 kV
 Supply

This diagnostic provides needed insight while avoiding historical challenges

- Present diagnostics tools external/outside the ion source
 - **External** voltage/current monitors, thermocouples
 - Need large, cumbersome **HV** Injection to measure emittance, beam current
 - H- Ion Source Test Stand (ISTS) has become more of a (very successful) beam injection R&D tool in the last few years.
 - Safety: Radiation hazards
- New H- Ion Source Laser diagnostic stand looks directly **into** ion source
 - **No high voltage extraction** makes for “benchtop tool” for more efficient experiments
 - Safety: No radiation hazards (albeit we introduce laser hazards)
 - Fast resolution (as low as $\sim 10 \mu\text{s}$) to diagnose intra-pulse effects
- Establish the diagnostic for accelerator based ion sources(*)
- Invaluable data for global ion source community

- **(As far as I know)*

How will this novel diagnostic improve LANSCE programmatic needs?

- Understanding time-dependent signatures of the Cs density will provide valuable tool to improve stability issues
 - What is correlation between Cs density and instabilities related to arc current transients? [1]
- H⁻ density will reveal the hidden neutralization mechanisms of H⁻ ions inside the H⁻ ion source.
 - $I_{H^-} = \sim 0.1 - 1$ A (hypothesized) at convertor, but only ~ 0.015 A (measured) downstream? Factor of x100?
 - *Even recovering a small amount of neutralized H⁻ could be revolutionary for LANSCE*
- Data for ion source modelling.

[1] Transients on Arc and Convertor currents in the Multi-cusp Cesium Surface Conversion H⁻ Source at LANSCE
2019 IEEE Pulsed Power & Plasma Science (PPPS), 2019, p. 1-4 (Kleinjan, D.)